Inventor:

T. L. Gilton

Title:

Switchable Circuit Devices

Assignee:

Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is

directed to the United States patents and other references listed on the attached

Form PTO-1449. No admission is made regarding whether all the submitted

references are prior art.

The listed references were cited by, or submitted to, the Office in the

parent, co-pending application of the above-identified application. The above-

identified application is a divisional application of co-pending application Serial

No. 10/177,242, filed June 21, 2002. Such prior disclosure is sufficient for the

above-identified application as far as copies of the references are concerned.

37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

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By:

David G. Latwesen, Ph.D.

Respectfully submitted,

Reg. No.

38,533

				DEPARTMENT OF COMMERCE	Γ				
Form PTO-14	49		ATTY. DOCKET NO. MI22-2428			<u>priority</u> SERIAL NO. 10/177,242			
		LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)			APPLICANT T. L. Gilton				
				priority FILING E June 21, 2002		ATE <u>priority</u> GROUP 2812			
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
	AA	6,187,604 B1	2/13/01	Gilton					
	АВ								•
	AC								
	AD								
	AE								
FOREIGN PATENT DOCUMENTS									
		Document	Date	Country		Class	Subclass	Trans	slation
		Number			 -			Yes	No
	AM						ļ	ļ	ļ
	AN						-	<u> </u>	ļ
	AO	L	<u> </u>			<u> </u>	<u> </u>		
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
	AR	Anodic Oxidation of Porous Silicon Layers Formed on Lightly p-Doped Substrates; A. Bsiesy et al; pp. 3450-3456; J. E Soc. Vol 138, No. 11; November 1991; The Electrochemical Society, Inc.							ctrochem.
	AS	Information and Properties of Porous Silicon Film, Yoshinobu Arita and Yoshio Sunohara; Journal of the Electrochemical Society: Vol. 124, No. 2; February 1977; pp. 285-295							Society;
		Building from the Bottom Up, Nano Technology; October 16, 2000; C & EN; pg. 27-32							
		New Tools for Tiny Jobs, Nano Technology; October 16, 2000; C & EN; pg. 33-35							
		Firms Find a New Field of Dreams; Nano Technology; October 16, 2000; C & EN; pg. 36-38							
	AT Crafting a National Nanotechnology Effort: Nano Technology: October 16, 2000; C & EN; pg. 39-42								
							<u> </u>		<u> </u>
EXAMINER			DATÉ CONSIDER	ED					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									